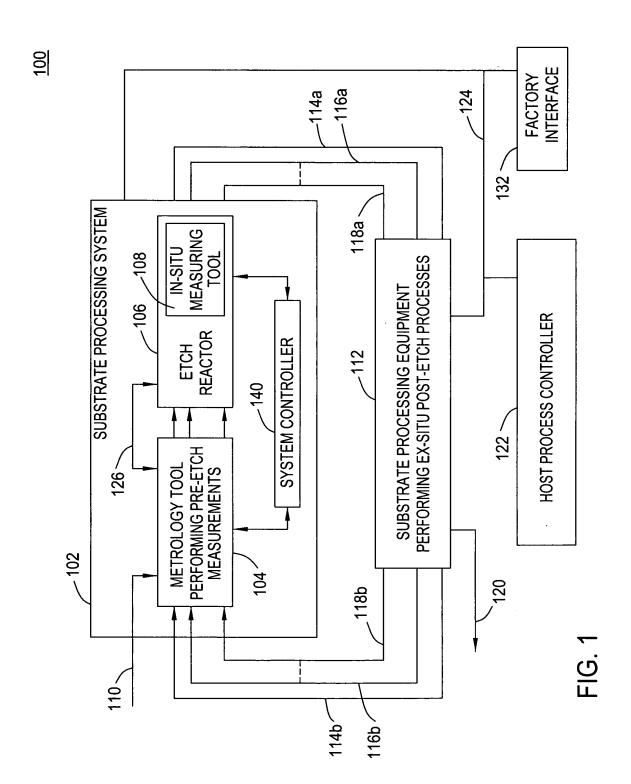
Sheet 1 of 13
Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A
MULTI-PASS PROCESS FOR
FABRICATING INTEGRATED DEVICES
Docket: 8381/ETCH/SILICON/JB1

1/13

 \neg



L

Sheet 2 of 13

Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A MULTI-PASS PROCESS FOR

FABRICATING INTEGRATED DEVICES Docket: 8381/ETCH/SILICON/JB1

2/13

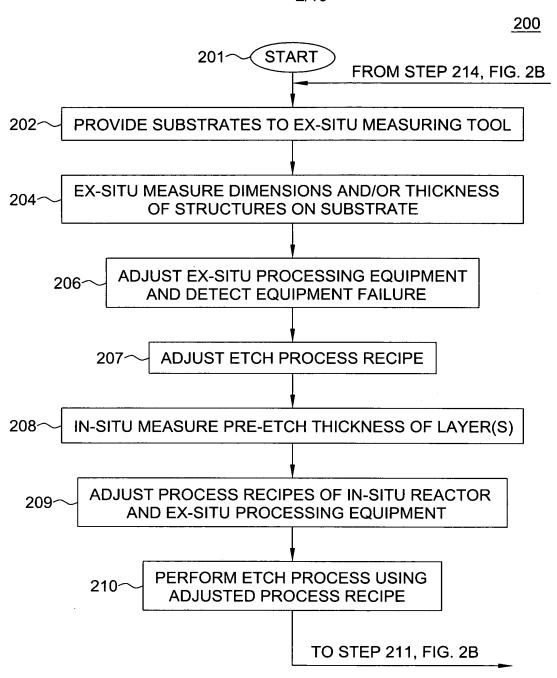
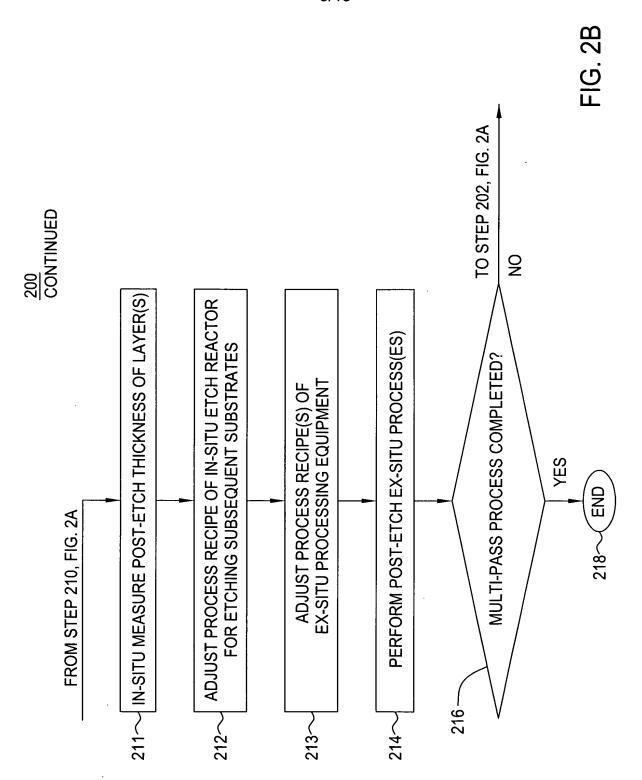


FIG. 2A

Sheet 3 of 13
Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A
MULTI-PASS PROCESS FOR
FABRICATING INTEGRATED DEVICES
Docket: 8381/ETCH/SILICON/JB1

3/13

 \neg



L

Sheet 4 of 13
Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A
MULTI-PASS PROCESS FOR
FABRICATING INTEGRATED DEVICES
Docket: 8381/ETCH/SILICON/JB1

 Γ

4/13

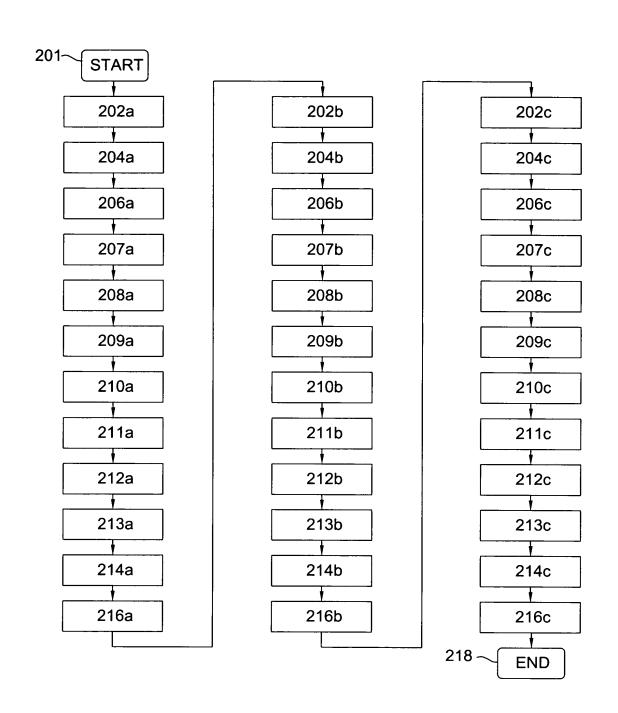


FIG. 2C

 \Box

Sheet 5 of 13

Γ

Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A
MULTI-PASS PROCESS FOR
FABRICATING TOTAL DEVICES Docket: 8381/ETCH/SILICON/JB1

5/13

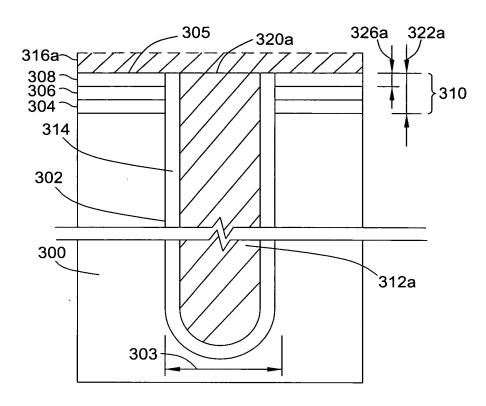


FIG. 3A

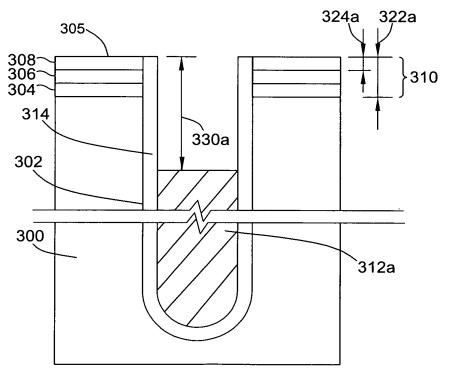


FIG. 3B

 Γ

Sheet 6 of 13
Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A
MULTI-PASS PROCESS FOR
FABRICATING INTEGRATED DEVICES
Docket: 8381/ETCH/SILICON/JB1

6/13

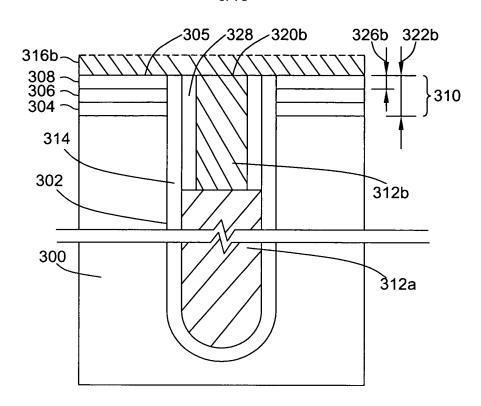


FIG. 3C

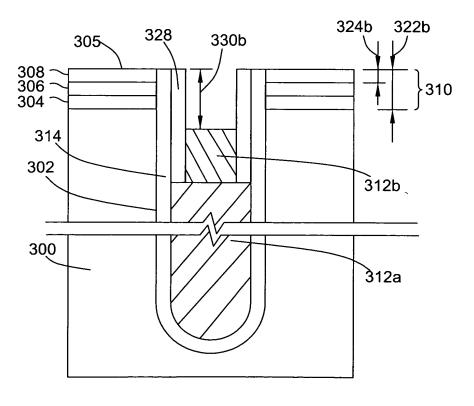


FIG. 3D

Sheet 7 of 13
Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A

MULTI-PASS PROCESS FOR FABRICATING INTEGRATED DEVICES Docket: 8381/ETCH/SILICON/JB1

7/13

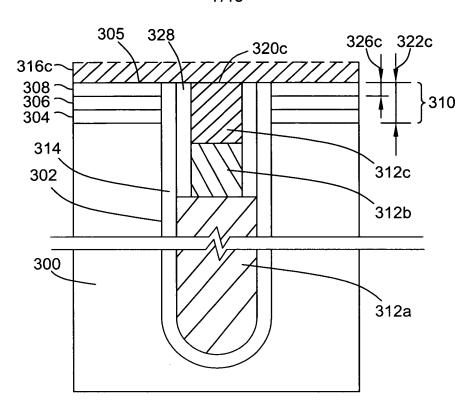


FIG. 3E

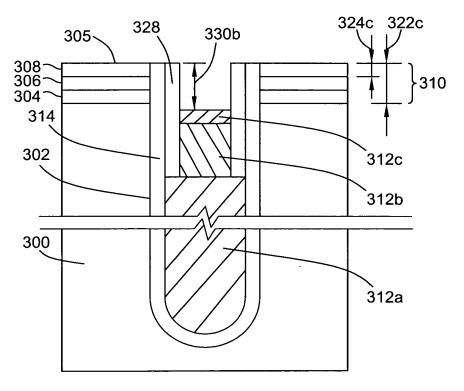
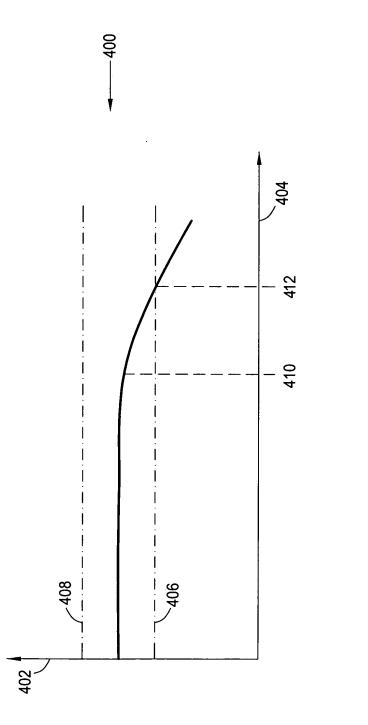


FIG. 3F

Sheet 8 of 13
Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A
MULTI-PASS PROCESS FOR
FABRICATING INTEGRATED DEVICES
Docket: 8381/ETCH/SILICON/JB1

8/13



 Γ

Sheet 9 of 13
Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A
MULTI-PASS PROCESS FOR
FABRICATING INTEGRATED DEVICES
Docket: 8381/ETCH/SILICON/JB1

9/13

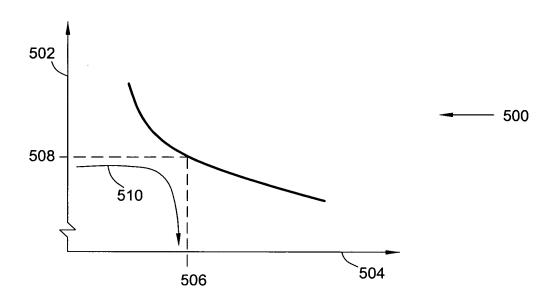
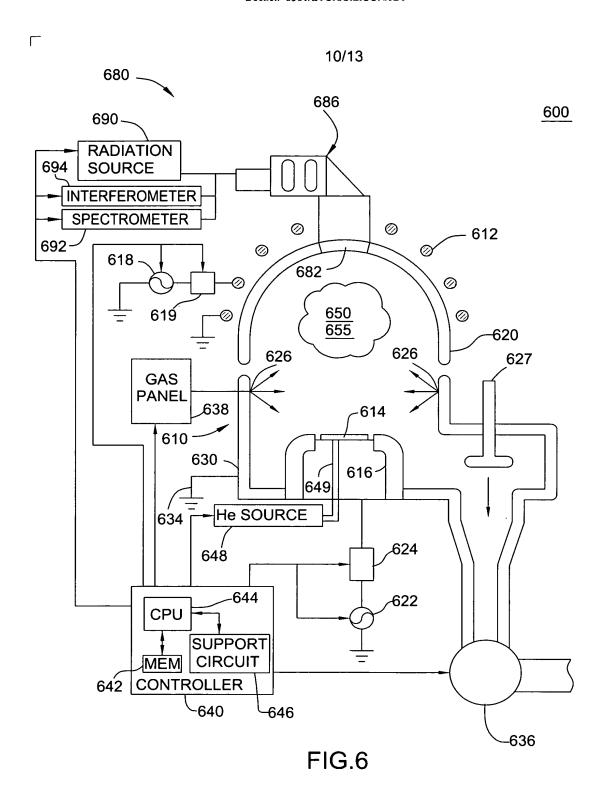


FIG.5

 \Box

Sheet 10 of 13 Applicant: Davis, et al. Title: METHOD FOR CONTROLLING A MULTI-PASS PROCESS FOR

FABRICATING INTEGRATED DEVICES Docket: 8381/ETCH/SILICON/JB1



Sheet 11 of 13

 Γ

Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A

MULTI-PASS PROCESS FOR FABRICATING INTEGRATED DEVICES Docket: 8381/ETCH/SILICON/JB1



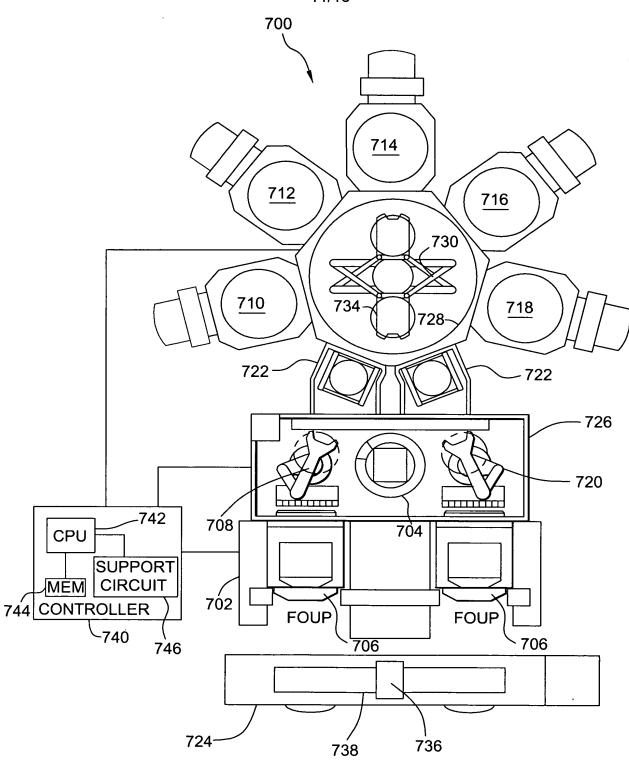
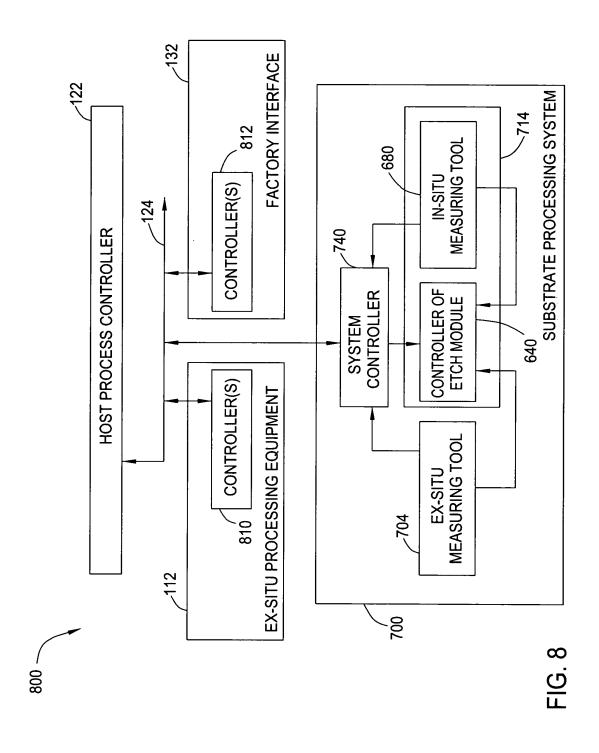


FIG. 7

Sheet 12 of 13
Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A
MULTI-PASS PROCESS FOR
FABRICATING INTEGRATED DEVICES
Docket: 8381/ETCH/SILICON/JB1

12/13

 \neg



L

Sheet 13 of 13

 Γ

Applicant: Davis, et al.
Title: METHOD FOR CONTROLLING A
MULTI-PASS PROCESS FOR
FABRICATING INTEGRATED DEVICES Docket: 8381/ETCH/SILICON/JB1

13/13

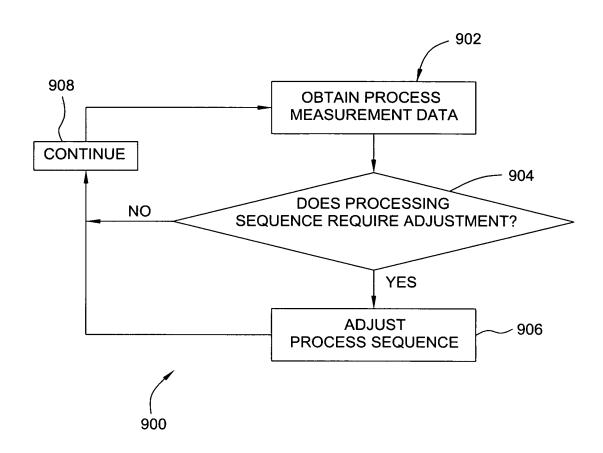


FIG.9